

00862.022199.



PATENT APPLICATION

8/A  
C. Jones  
12/1/03

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,  
ELECTRON BEAM LITHOGRAPHY  
APPARATUS, EXPOSURE APPARATUS,  
EXPOSURE APPARATUS MAINTENANCE  
METHOD, SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD, AND SEMI-  
CONDUCTOR MANUFACTURING FACTORY

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: Examiner: P. Rodriguez  
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: Group Art Unit: 2125  
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: Confirmation No.: 4154  
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:  
) November 19, 2003  
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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RECEIVED**

NOV 25 2003

Technology Center 2100

AMENDMENT AND LETTER  
FORWARDING SUBSTITUTE SPECIFICATION

Sir:

In response to the Official Action dated August 19, 2003, please amend the above-  
identified application as follows:

11/21/2003 HLE333 00000040 09833766

01 FC:1201  
02 FC:1202

688.00 DP  
36.00 DP